

#### 2019 Refinement to the 2006 IPCC Guidelines: Refinements in Volume 3 (Industrial Process and Product Use)

Bonn Climate Change Conference (SB50) SBSTA - IPCC Special Event on 2019 Refinement to the 2006 IPCC Guidelines

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#### What is IPPU?

#### Industrial Processes and Product Use (IPPU) – Greenhouse Gas (GHG) emissions (!):

1. Industrial Processes

that chemically or physically transform materials releasing GHGs:

- chemically:  $NH_3 + O_2 = 0.5 N_2O\uparrow + 1.5 H_2O$  (nitric acid production)
- physically: CaCO<sub>3</sub> + (Heat) = CaO + CO<sub>2</sub>↑ (cement production)
- 2. Product Use

GHGs are used in products such as refrigerators, foams or aerosols

#### Note:

All emissions from combustion of fossil fuels in Industry are under Energy Sector. IPPU focuses on process emissions





### Mandate for Refinement (IPPU)

**Chapter 3** 

- **o** Nitric acid production
- Fluorochemical production
- Hydrogen production [New]

**Chapter 4** 

- $\circ~$  Iron and Steel
- Primary aluminium production and Alumina production [New]
- Rare Earths elements [New]

**Chapter 6** 

• Electronics Industry

Chapter 7

• Refrigeration and air conditioning

**Chapter 8** 

 Use of SF6 and PFCs in Textile Industry and for Water-proofing of electronic circuit boards [New]

> ✓ Decision IPCC/XLIV-5 IPCC-44, Bangkok (Thailand), October 2016

#### IPPU Refinement – 2006 Structure



#### Nitric Acid Production – N2O

Update of N<sub>2</sub>O emission factors for various types of technologies used for Nitric Acid production:

- single-/duo- low-/medium- /high- pressure plants
- with or without abatement

TABLE 3.3 (UPDATED)Default factors for nitric acid production		
Production Process	N <sub>2</sub> O Emission Factor (relating to 100 percent pure acid)	
Old (pre-1975) plants* (all processes)	10-19 kg N <sub>2</sub> O/tonne nitric acid <sup>a</sup>	
Single low pressure plants	5 kg N <sub>2</sub> O/tonne nitric acid $\pm 10\%$	
Single medium pressure plants	8 kg N <sub>2</sub> O/tonne nitric acid $\pm 20\%^{b}$	
Single high pressure plants	9 kg N <sub>2</sub> O/tonne nitric acid ±40%	
Single pressure plants with abatement technology**	2.5 kg N <sub>2</sub> O/tonne nitric acid $\pm 10\%^{b}$	
Dual Pressure (M/H)	9 kg N <sub>2</sub> O/tonne nitric acid $\pm 30\%^{b}$	
Dual Pressure (M/H) with abatement technology	2.5 kg N <sub>2</sub> O/tonne nitric acid $\pm 20\%^{b}$	
Dual Pressure (L/M)	7 kg N <sub>2</sub> O/tonne nitric acid $\pm 20\%^{b}$	
Dual Pressure (L/M) with abatement technology	1.5 kg N <sub>2</sub> O/tonne nitric acid ±10% <sup>b</sup>	



#### **Fluorochemical Production**

- Improved guidance on GHG emissions from production of fluorinated compounds (other than HFC-23 emissions from HCFC-22 production)
- These emissions include emissions of the intentionally manufactured chemical as well as reactant and by-product emissions.
  - For example, in a national inventory for a fluorochemical plant, significant byproduct emissions of SF6, CF4, C2F6, C3F8, C4F10, C5F12 and C6F14 were reported
  - Other examples include the release of by-product N2O and CF4 from the production of NF3
- Streamlined categories

2006 IPCC Guidelines		2019 Refinement		
2B9 Fluorochemical	Fluorochemical uction2B9a By-Product emissions2B9 Fluorochemical Production2B9b Fugitive emissionsProduction	2B9 Fluorochemical	2B9a HCFC-22 Production	
Production		2B9b HFC Production		
			2B9c PFC Production	
			2B9d SF6 Production	
			2B9e NF <sub>3</sub> Production	
			2B9f Fluoropolymer Production	
			2B9g Other Fluorochemical Production	



## Hydrogen Production – CO<sub>2</sub>

- New category for stand-alone facilities which produce only Hydrogen as a main product
- Hydrogen can be produced in Refineries as well (2006 IPCC Guidelines)
- The method is similar to Methanol and Ammonia production SynGas technology (steam reforming and gasification)
- Focus on fossil fuels (!) which provide Hydrogen and Carbon (subsequently CO<sub>2</sub>)





#### Iron and Steel Production – CO2

- Clarified guidance on demarcation between Energy and IPPU – all emissions from Coke Production emissions are in Energy (as in 2006 IPCC Guidelines)
- Updated CO<sub>2</sub> emission factors
- Improvements on BFG/LDG flaring (CO<sub>2</sub>, N<sub>2</sub>O) and nonfugitives CH<sub>4</sub> emissions





## Aluminium – PFCs (CF4 and C2F6)

- CO₂ guidance is unchanged
- PFCs guidance is improved taking into account a new phenomena on the low-voltage anode effects (LVAE) added to previously known the high-voltage anode effect (HVAE)

TABLE 4.15 (UPDATED) TECHNOLOGY SPECIFIC DEFAULT EMISSION FACTORS FOR THE CALCULATION OF HVAE AND LVAE EMISSIONS FROM ALUMINIUM PRODUCTION (TIER 1 METHOD) (MARKS & NUNEZ 2018B)						
Technology	chnology HVAE LVAE				AE	
	CF4		C	2F6	C	F4
	EFCF4 (kg/tonne Al)	Uncertainty Range (%) <sup>b</sup>	EFc2F6 (kg/tonne Al)	Uncertainty Range (%)	EFcF4 (kg/tonne Al)	Uncertainty Range (%)
$\mathbf{PFPB}_{\mathbf{L}}$	0.016 <sup>a</sup>	-82/+126 <sup>a</sup>	0.001	-74/+109 <sup>a</sup>	0.009 <sup>a</sup>	+99/-61
PFPB <sub>M</sub>	0.011	-90/+213	0.001	-90/+256	0.018	+247/-98
PFPB <sub>MW</sub>	0.161 <sup>b</sup>	-85/+476	0.013 <sup>b</sup>	-98/+864	-	-
SWPB	0.354	-76/+116	0.093	-89/+68	0.010	+69/-69
VSS	0.159°	-94/+580°	0.009°	-94/+525	0.001	+61/-52
HSS	0.477	-79/+112	0.033	-76/+86	0.026	_d



### Alumina Production – CO<sub>2</sub>

- Methodological issues for particular technologies are only considered (Bayer-sintering parallel (BSP), Bayer-sintering sequential (BSS) and Nepheline processing (NP) – for <u>Alumina</u> Production)
- It is estimated that only around 3% of alumina was produced globally via the Bayer-sintering process and around 1% via the Nepheline processing mainly in 3 countries – Russia, Kazakhstan and China
- 2006 IPCC Guidelines already considered fossil fuel combustion (Chapter 2 Volume 2) and lime production (Chapter 2 Volume 3). Check lime activity data for double counting!

TABLE 4.17A (NEW) Technology specific default emission factors for the calculation of CO <sub>2</sub> emissions from alternative sintering processes (Tier 1 method)			
Technology	EF <sub>SintAl2O3</sub> (tonne CO <sub>2</sub> /tonne Al) <sup>a</sup>	Uncertainty Range (%) <sup>b</sup>	
Bayer-sintering (BSP and BSS)	0.81	-8/+4	
Nepheline-sintering process (NP)	2.46	-2/+4	



#### **Rare Earths Production – CO2 and PFCs**

- New category. Rare Earths Production is an electrolytic process similar to Aluminium Production
- Emissions of CO<sub>2</sub> and PFCs (CF4, C<sub>2</sub>F6, C<sub>3</sub>F8)

Table 4.28 (new)   Tier 1 default emission factors and uncertainty ranges for the calculation of PFC emissions from rare earth production						
	CF4		C2F6		C3F8	
Rare Earth Metal, <i>i</i>	<i>EF<sub>CF4</sub></i> (g/tonne RE metal)	Uncertainty Range <sup>c</sup> (+/-%)	EF <sub>C2F6</sub> (g/tonne RE metal)	Uncertainty Range <sup>c</sup> (+/-%)	<i>EF<sub>C3F8</sub></i> (g/tonne RE metal)	Uncertainty Range <sup>c</sup> (+/-%)
RE-iron alloys (Dy-Fe, etc) <sup>a</sup>	146.1	+/- 99%	14.6	+/- 99%	0.05	+/- 99%
Other-RE metals/alloys (Nd, Pr-Nd, La, etc) <sup>b</sup>	35.8	-54% / +30%	5.2	-95% / +108%	0.21	-52% / +30%



#### **Electronics Industry**

- The guidance was substantially updated taking into account dynamic changes in the industry (production of semiconductors, displays, photovoltaics, etc.)
- The categories are almost the same with addition of Microelectromechanical systems. Fluorinated liquids are estimated under each sub-category
- Tier 1 and Tier 2 emission factors were updated with increased number of species
- Variety of gases (N<sub>2</sub>O, SF<sub>6</sub>, NF<sub>3</sub>, HFCs, PFCs)





### **Refrigeration and Air Conditioning**

- According to the mandate the guidance on "How to build a refrigeration and air conditioning emission inventory in a few simple steps" was developed
- Some updated information regarding emission factors for refrigerants (HFCs) was provided
- An example MS Excel worksheet was produced to facilitate emissions estimations for Tier 2





#### **Other Product Manufacture and Use**

#### Water-proofing of electronic circuit boards

Fluorinated compounds are used to waterproof electronic circuits (by gas-phase reaction in a plasma). The plasma deposition process involves the introduction of a variety of hydrocarbon gases, where the hydrogen atoms are replaced by fluorine supplied from a fluorinated gas source decomposed in a plasma. Periodically, the process chamber is also cleaned using fluorinated gases in a way similar to one in Electronics industry.

Table 8.11 (new)Emission factor for waterproofing of electronic circuits			
Gas Emitted	Emissions (g)/Circuit Board		
CF4	0.006		
C <sub>2</sub> F <sub>6</sub>	0.004		
CHF <sub>3</sub>	0.003		

#### **Textile Industry**

As in Electronics Industry, plasma-based processes using fluorinated compounds in the textile industry are expected to result in emissions of unreacted fluorinated compounds and by-products with high global warming potentials (GWPs). However, the extent to which plasma processes have been introduced in textile manufacturing is not clear. Also, the wet application of fluorinated compounds commonly used to treat textile, carpet, leather, and paper fibres can result in emissions of volatile fluorinated compounds through evaporative losses and cracking.

• This guidance was moved to Appendix. Authors could not develop default emission factors for Textile Industry. Basis for future work

### New 2019 IPPU Structure



#### Conclusion

- Only particular categories were refined, where there is a need to update emission factors and methodological guidance and to provide new information
- More complete coverage of sources and gases, some of categories are minor ones in terms of emissions
- Structure of categories is practically the same. Main categories are already covered in 2006 IPCC Guidelines
- F-gases emissions are evolving all the time (a challenge for developing emission factors). IPCC guidelines provide with default emission factors, countries can use their own factors







# Thank you

https://www.ipcc-nggip.iges.or.jp/index.html

